Listing of the Claims:

This listing of claims will replace all prior versions and listings of claims in the application.

Listing of Claims:

1. (Previously Presented) A system for positioning a product, comprising a chuck for supporting the product, an intermediate stage supporting said chuck, and a stationary base supporting said intermediate stage, whereby the chuck can move with respect to the intermediate stage in a first direction X, and the intermediate stage can move with respect to said stationary base in a second direction Y, furthermore comprising at least a first and a second laser interferometer for measuring the position of the chuck relative to the stationary base, a first and a second main part of said respective first and second laser interferonmeters including optical components for receiving and directing a first and a second laser respectively, the first and second main parts being attached to said intermediate stage and being movable therewith for measuring respectively the distance between a first elongated plane mirror reflector on the chuck that is elongated in the first direction X and an elongated plane mirror reflector on the stationary base that is elongated in the second direction Y, and the distance between a second elongated plane mirror reflector on the chuck that is elongated in the first direction X and the elongated plane mirror reflector on the stationary base.

2. (Previously Presented) A system as claimed in claim 1, the elongated plane mirror reflector on the stationary base having a length larger than the maximal displacement of the intermediate stage in said second direction Y.

3. (Previously Presented) A system as claimed in claim 1, further comprising a third laser interferometer having a main part that is attached to saidstationary base, the main part including optical components for receiving and directing a third laser for

measuring the distance between a third elongated reflector on the chuck that is elongated in the first direction X and the main part on the stationary base.

4. (Previously Presented) A system as claimed in claim 1, further comprising three laser interferometers each having a main part, the respective main parts of the three laser interferometers are attached to said intermediate stage and movable therewith, for measuring distances in the first direction X between one or more first reflectors on the chuck and one or more plane mirror reflectors in the stationary base.

5. (Previously Presented) A system as claimed in claim 1, the chuck further comprising a cube corner reflector.

6. (Previously Presented) A system as claimed in claim 1, wherein the first and second main parts are attached to said intermediate stage for measuring respectively the distance in the third direction Z between the first elongated plane mirror reflector on the chuck and the elongated plane mirror reflector on the stationary base, and the distance in the third direction Z between the second elongated plane mirror reflector on the chuck and the elongated plane mirror reflector on the stationary base, which third direction Z is perpendicular to the first direction X and the second direction Y.

7. (Previously Presented) A method for positioning a product by means of a system comprising a chuck for supporting the product, an intermediate stage supporting said chuck, and a stationary base supporting said intermediate stage, whereby the chuck can move with respect to the intermediate stage in a first direction X, and the intermediate stage can move with respect to said stationary base in a second direction Y, the method comprising attaching at least a first and a second laser interferometer to the intermediate stage, the first and second laser interferometers respectively further comprising a first and a second main part including optical components for receiving and directing a first and a second laser, the first and second main parts being movable with the intermediate stage, and measuring the position of the chuck relative to the stationary base by measuring a

first distance between a first elongated reflector on the chuck and an elongated reflector on the stationary base using the first laser interferometer, and a second distance between a second elongated reflector on the chuck and the elongated reflector on the stationary base using the second laser interferometer .

8. (Previously Presented) A method as claimed in claim 7, wherein the first and second elongated reflectors on the chuck are elongated in the first direction X and the elongated reflector on the stationary base is elongated in the second direction Y.

9. (Previously Presented) A method as claimed in claim 7, further comprising moving the chuck relative to the stationary base and measuring the position of the chuck relative to the stationary base during such movement.